	RH=55%	RH=70%	RH=85%
55ºC	72.5 hrs	35.5 hrs	19.6 hrs
65ºC	34.8 hrs	16.9 hrs	9.5 hrs
75ºC	17.5 hrs	8.5 hrs	4.7 hrs

Fig. 1

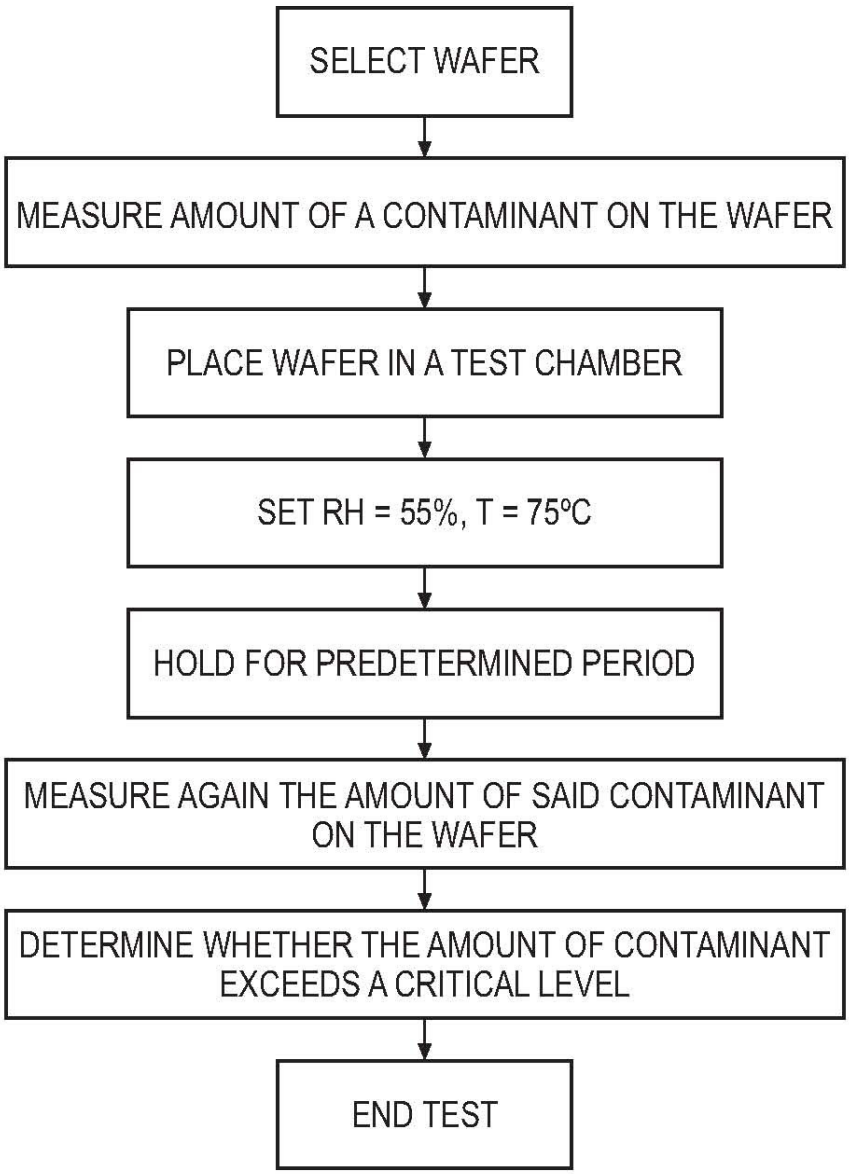

SELECT WAFER
MEASURE AMOUNT OF A CONTAMINANT ON THE WAFER
PLACE WAFER IN A TEST CHAMBER
SET RH = 55%, T = 75ºC
HOLD FOR PREDETERMINED PERIOD
MEASURE AGAIN THE AMOUNT OF SAID CONTAMINANT ON THE WAFER
DETERMINE WHETHER THE AMOUNT OF CONTAMINANT EXCEEDS A CRITICAL LEVEL
END TEST

Fig. 2

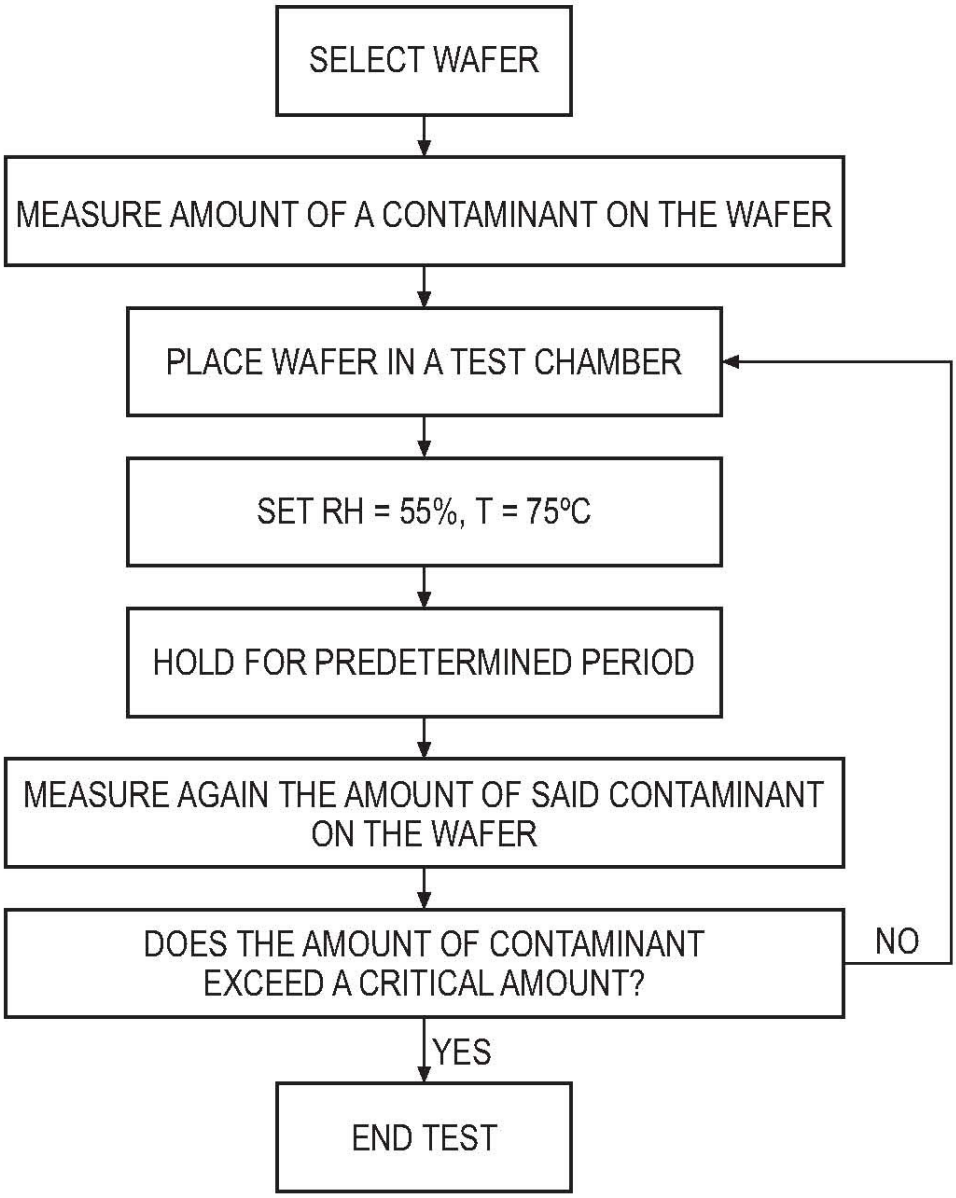

SELECT WAFER
MEASURE AMOUNT OF A CONTAMINANT ON THE WAFER
PLACE WAFER IN A TEST CHAMBER
SET RH = 55%, T = 75°C
HOLD FOR PREDETERMINED PERIOD
MEASURE AGAIN THE AMOUNT OF SAID CONTAMINANT ON THE WAFER
DOES THE AMOUNT OF CONTAMINANT EXCEED A CRITICAL AMOUNT?
NO
YES
END TEST

Fig. 3